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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet

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Complete if Known

Application Number	09/905,718
Filing Date	May 16, 2002
First Named Inventor	Watts et al.
Group Art Unit	1762
Examiner Name	Bernard D. Pianalto
Attorney Docket Number	PA27/UTS-26-03q12

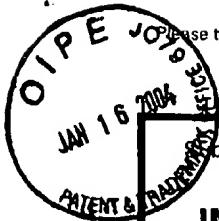
U.S. PATENT DOCUMENTS

Examiner Initials*	Cita No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
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	A3	3,811,665		Seelig	05-21-1974	
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	A6	4,155,169		Drake et al.	05-22-1979	
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Examiner Signature	Pianalto		Date Considered	7-29-04		

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Attorney Docket Number	PA27/UTS-26-03q12

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	A36	5,723,176		Keyworth et al.	03-03-1998	
	A37	5,724,145		Kondo et al.	03-03-1998	
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Pianalto

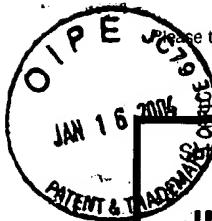
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		Office ³	Number ⁴	Kind Code ⁵ (if known)			
	A71	DE	2800476		Lamprecht et al.	07-13-1978	
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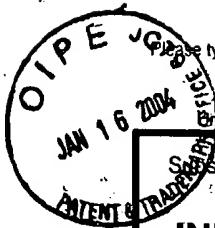
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OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
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OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS

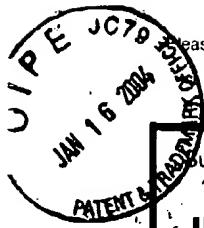
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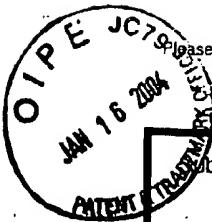
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BL	A123	KOSEKI et al., "Design and Accuracy Evaluation of High-Speed and High-Precision Parallel Mechanism," Proc. of the 1998 IEEE, Intl. Conf. on Robotics & Automation, May 1998, pp. 1340-1345, Leuven, Belgium.	
	A124	KIM et al., "High Precision Magnetic Levitation Stage for Photolithography," Precision Engineering, 1998, pp. 66-77, vol. 22, Elsevier Science Inc., 655 Avenue of the Americas, NY, NY 10010. <i>(No month avail.)</i>	
	A125	MANSKY et al., "Large-Area Domain Alignment in Block Copolymer Thin Films Using Electric Fields," Macromolecules, 1998, pp. 4399-4401, vol. 31. <i>(No month avail.)</i>	
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	A127	SCHEER et al., "Problems of the Nanoimprinting Technique for Nanometer Scale Pattern Definition," Journal of Vacuum Science and Technology, Nov/Dec 1998, pp. 3917-3921, vol. B 16(6).	
	A128	XIA et al., "Soft Lithography," Annu. Rev. Mater. Sci., 1998, pp. 153-184, vol. 28. <i>(No month avail.)</i>	
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	A130	TAJBAKHSH et al., "Three-Degree-of-Freedom Optic Mount for Extreme Ultraviolet Lithography," ASPE, 1998, pp. 359-362, vol. 18. <i>(No month avail.)</i>	
	A131	LEE et al., "Ultra Precision Positioning System for Servo Motor-Piezoelectric Actuator Using the Dual Servo Loop and Digital Filter Implementation," ASPE, 1998, pp. 287-290, vol. 18. <i>(No month avail.)</i>	
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	A133	OHYA et al., "Development of 3-DOF Finger Module for Micro Manipulation," Proc. of the 1999 IEEE/RSJ, Intl. Conf. on Intelligent Robots and Systems, 1999, pp. 894-899. <i>(No month avail.)</i>	

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				Application Number	09/905,718
				Filing Date	May 16, 2002
				First Named Inventor	Watts et al.
				Group Art Unit	1762
				Examiner Name	Bernard D. Pianalto
Sheet	8	of	9	Attorney Docket Number	PA27/UTS-26-03q12

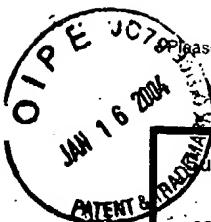
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<p style="text-align: center;">B.P.</p>	A134	TANIKAWA et al., "Development of Small-Sized 3 DOF Finger Module in Micro Hand for Micro Manipulation," Proc. of the IEEE/RSJ, Intl. Conf. on Intelligent Robots and Systems, 1999, pp. 876-881. <i>(No month avail.)</i>
	A135	COLBURN. et al., "Step and Flash Imprint Lithography: A New Approach to High-Resolution Patterning", Proc. of SPIE, 1999, pp. 379-389, vol. 3676. <i>(No month avail.)</i>
	A136	Lucas Aerospace, Free-Flex Pivot Catalog, 1999. <i>(No month avail.)</i>
	A137	GOLDFARB et al., "A Well-Behaved Revolute Flexure Joint for Compliant Mechanism Design," Journal of Mech. Design, Sept. 1999, pp. 424-429, vol. 121.
	A138	Geodetic Technology, G1000-PC Power Series Specifications, 1999, from www.hexapods.com. <i>(No month avail.)</i>
	A139	Hexel Corporation, Tornado 2000 System Specifications, 1999, from www. Hexel.com. <i>(No month avail.)</i>
	A140	Physik Instruments, PI Online-Catalog, 1999, from www. Physikinstruments.com. <i>(No month avail.)</i>
	A141	CHOU et al., "Lithographically-Induced Self Assembly of Periodic Polymer Micropillar Arrays," Journal of Vacuum Science and Technology, Nov/Dec 1999, pp. 3197-3202, vol. B 17(6).
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	A143	Vanderbilt University Office of Transfer Technology, VU 9730 Specifications for Improved Flexure Device; 2001, from www.vanderbilt.com. <i>(No month avail.)</i>
	A144	STIX, "Getting More from Moore's," Scientific American, 2001, from www.scientificamerican.com. <i>(No month avail.)</i>

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BH	A145	CHOI et al., "High Precision Orientation Alignment and Gap Control Stages for Imprint Lithography Processes," U.S. Patent Application 09/698,317, Filed with USPTO on October 27, 2000.	
	A146	SREENIVASAN et al., "High-Resolution Overlay Alignment Methods and Systems for Imprint Lithography," U.S. Patent Application 09/907,512, Filed with USPTO on July 16, 2001.	
	A147	CHOI et al., "Method and System of Automatic Fluid Dispensing for Imprint Lithography Processes," U.S. Patent Application 09/908,455, Filed with USPTO on July 17, 2001	
	A148	WILLSON et al., "Step and Flash Imprint Lithography," U.S. Patent Application 09/908,765, Filed with USPTO on July 19, 2001.	
	A149	CHOI et al., "Methods for High-Precision Gap and Orientation Sensing Between a Transparent Template and Substrate for Imprint Lithography," U.S. Patent Application 09/920,341, Filed with USPTO on August 1, 2001.	
	A150	Nguyen, A. Q., "Asymmetric Fluid-Structure Dynamics in Nanoscale Imprint Lithography," University of Texas at Austin, August 2001.	
	A151	CHOI et al., "Flexure Based Macro Motion Translation Stage," U.S. Patent Application 09/934,248, Filed with USPTO on Auguts 21, 2001.	
	A152	BAILEY et al., "Template for Room Temperature Low Pressure Micro- and Nano-Imprint Lithography," U.S. Patent Application 09/976,681, Filed with USPTO on October 12, 2001.	
	A153	WATTS et al., "Low Viscosity High Resolution Patterning Material," U.S. Patent Application 10/178,947, Filed with USPTO on June 24, 2002.	

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